Comparison of Radiation Hardness Properties of p⁺n⁻ & n⁺p⁻ Si Strip Sensors Using Simulation Approach

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Contents of presentation

- Simulation framework
- Comparison of Interstrip properties of p-in-n and n-in-p sensors
 - Cint comparison
 - Rint comparison

E field comparison of p-in-n and n-in-p type irradiated strip sensor

Correlation with measured non-Gaussian Noise

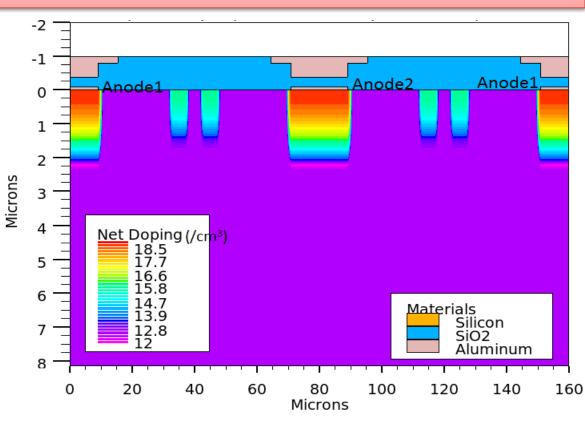
***** E field simulations for irradiated p-in-n sensors :

- Effect of oxide charge density variation
- Measured non-Gaussian noise for different type of irradiation
- Effect of strip pitch variation
 - Measured non-Gaussian noise for different pitch
- Effect of temperature variation
 - Comparison with measurements

Summary

Simulation structure

- Bulk doping = 3e12cm-3
- 2-D simulations
- For n+p- sensors
- -Double p-stops (P-type)
- Each 4µm wide separated by 6µm
- P-stop doping = 5e15cm-2P-stop doping depth = 1.6um
- CMS HPK tracker upgrade campaign parameters [1]
- Simulations using Silvaco TCAD



A . Deirlamm, 2012 JINST 7 C01110 , THE 9th INTERNATIONAL CONFERENCE ON POSITION SENSITIVE DETECTORS, 12–16 SEPTEMBER 2011,



Bulk + Surface damage model

- Two more acceptors & one donor in addition to two deep levels
- Able to remove accumulation e-
- Produce very high E field near n+
- Reproduce experimental observed Rint and Cint

Turn	Energy Land	Tradana	- (2)	- (2)
Trap	Energy Level	Intro.	σ_{e} (cm ⁻²)	$\sigma_{\rm h}({\rm cm}^{-2})$
Acceptor	0.525eV	3.0	1x10 ⁻¹⁴	1.4x10 ⁻¹⁴
Acceptor	0.45eV	40	8x10 ⁻¹⁵	2x10 ⁻¹⁴
Acceptor	0.40eV	40	8x10 ⁻¹⁵	2x10 ⁻¹⁴
Donor	0.50eV	0.6	4x10 ⁻¹⁴	4x10 ⁻¹⁴
Donor	0.45eV	20	4x10 ⁻¹⁴	4x10 ⁻¹⁴

Along with radiation damage (fluence, particle type), oxide charge density is a complex function of fabrication process, annealing steps, humidity etc.

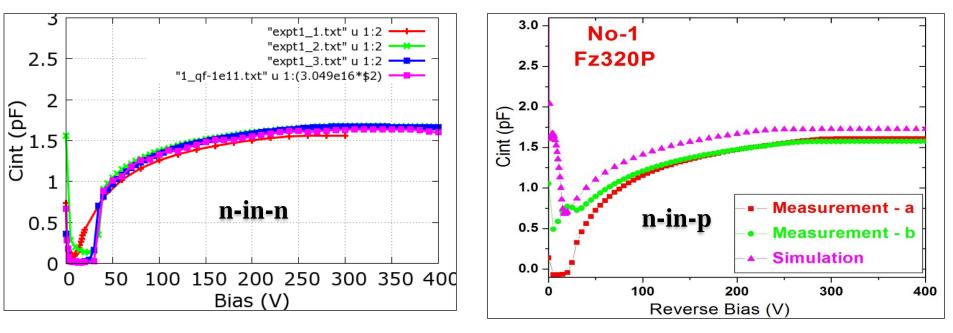
Hence, instead of taking one value of Q_F , for a given flux of hadron irradiation, surface damage is incorporated in simulation by considering range of Q_F for a given fluence.

Ranges of Oxide charge density (Q_F) used

Irradiation fluence (neq/cm ²)	Range of Q _F (cm ⁻²)
0	5e10 to 5e11
1x10 ¹⁴	1e11 to 8e11cm-2
5x10 ¹⁴	5e11 to 1.2e12
1x10 ¹⁵	8e11 to 2e12

Simulation of strip sensor : C_{int} vs. V_{bias} (un-irradiated)

Simulation vs. Measurement

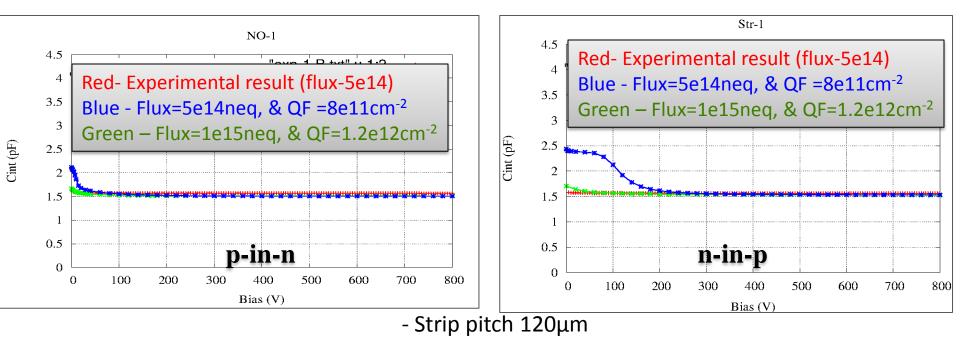


- Strip pitch 120 μ m

• Simulations are mostly in good agreement with measurements for both p-in-n and n-in-p type of strip sensors.

Simulation of strip sensors : C_{int} vs. V_{bias} (Irradiated)

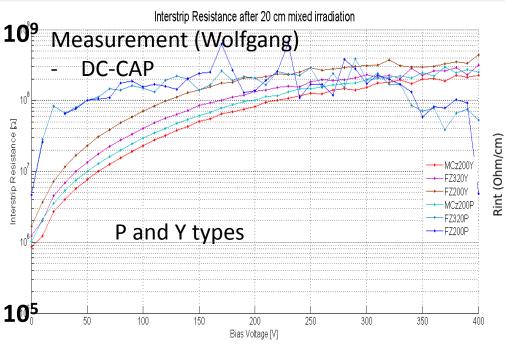
Simulation vs. Measurement



Simulation is mostly in good agreement with measurements for both p-in-n and n-in-p type strip sensor
C_{int} is quite similar for both type of sensors

Simulations vs measurement : R_{int} for n-in-p sensor

- Ranjeet, Delhi Uni. 23rd RD-50 workshor

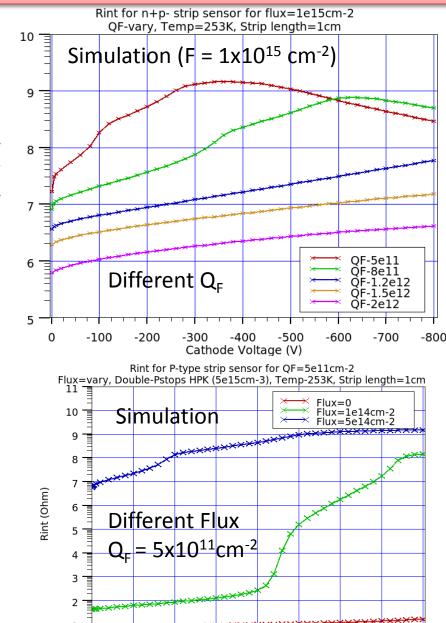


• Simulated R_{int} show trends similar to the Measurements.

• R_{int} decreases on increasing the Q_{F} • R_{int} is a strong function of the combination of surface damage (Q_{F}) and Bulk Damage (flux). Bulk damage compensates for surface damage.

 \bullet Good isolation even at high flux and high $Q_{F^{\bullet}}$

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-100

-200

-300

-400

Cathode Voltage (V)

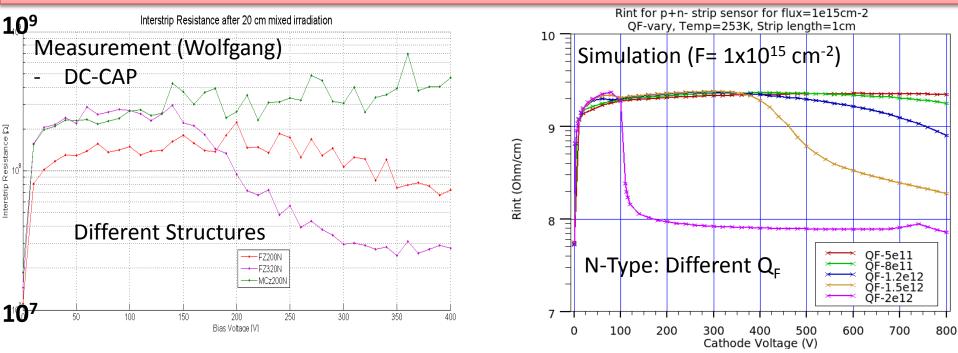
-500

-600

-700

-800

Simulations vs measurement : R_{int} for p-in-n sensor

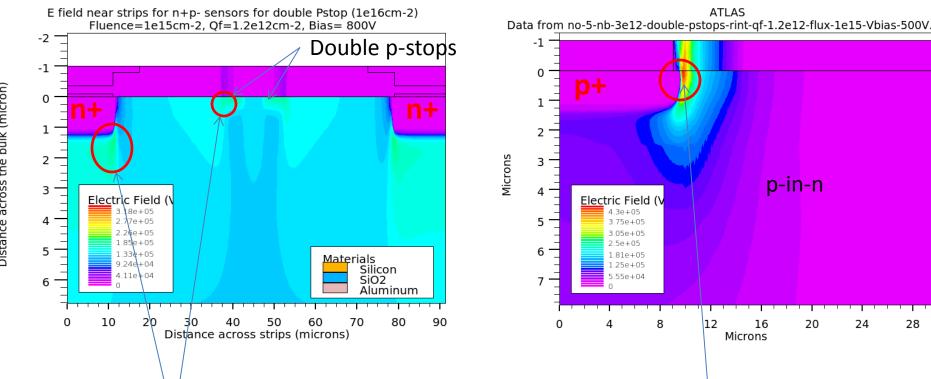


 \succ Isolation remains good for all values of Q_F.

> Simulation shows decrease in R_{int} for high values of Q_F at high Bias values. Experimentally different structures show similar behaviour.

> Electric field near the curvature of p+ strip is quite high & increases with Q_F . This high E field can initiate a localized avalanche & can decrease R_{int}

Maximum E field regions in p-type and n-type sensors



Maximum E field for n+p- MSSD is near the curvature region of n+ strip Or just near p-stop, just below SiO2/Si interface - Shown by cutline 1.3µm below SiO2/Si interface

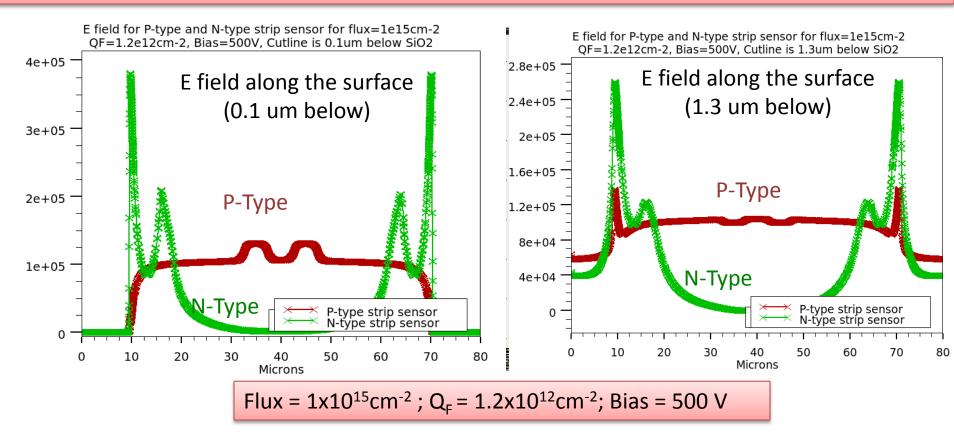
Maximum E field for p+n- MSSD is just below SiO2/Si interface - Shown by cutline 0.1µm below SiO2

Effect of very high E field in irradiated sensor

- E field inside irradiated sensors is a strong function of space charge .
- > Very high E field in a region can initiate avalanche in that region.
- Once avalanche is started, a lot of free e/h pairs are produced which will compensate the nearby space charge, changing the electric field, thus stopping the further breakdown.

This mechanism may stop the avalanche from turning global and continuous. Thus high E field near the strips can be a reason of non – Gaussian noise events which occur randomly (RGH- Random Gaussian Hits)

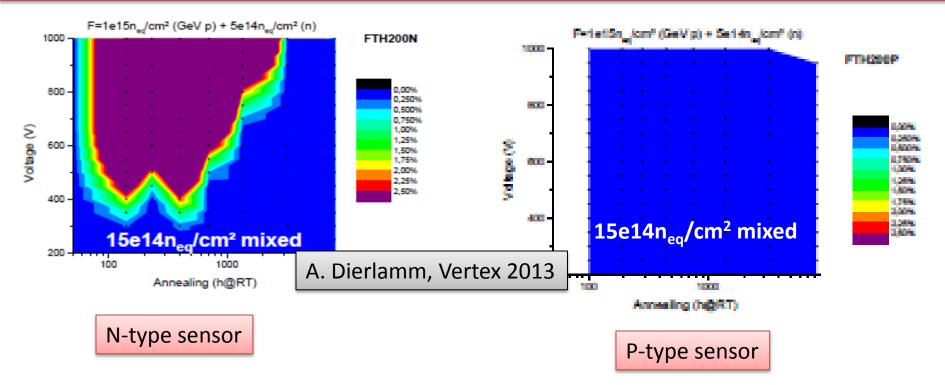
E. Field (Irradiated) comparison : p-in-n & n-in-p sensor



• Peak electric field is more for p-in-n (n-type) sensor as compared to n-in-p (p-type) sensor for a given bias.

• Micro-discharge possibility is much more in p-in-n sensors.

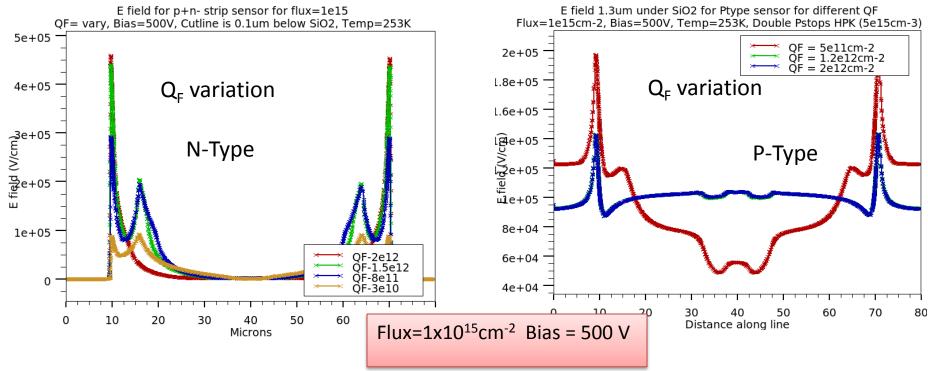
Amount of RGH for irra. n-type and p-type of sensor



Significant amount of non-Gaussian noise (RGH) observed in p-in-n sensor (n-type)
 Very less amount of RGH rates observed for n-in-p (p-type) sensor



E. Field (Irradiated) : Effect of Q_F



• N-type sensors (p-in-n)

- As Q_F increases = > Peak Efield increases.
- Micro-discharge possibility is more in N-type sensors after proton irradiation or less possibility after neutron irradiation

• P-type (n-in-p)

•Peak field is much less compare to p-in-n sensors

• As Q_F increases = > Peak E field decreases.

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RGH for different type of irradiation (for p-in-n)

7e14n_{eq}/cm² mixed

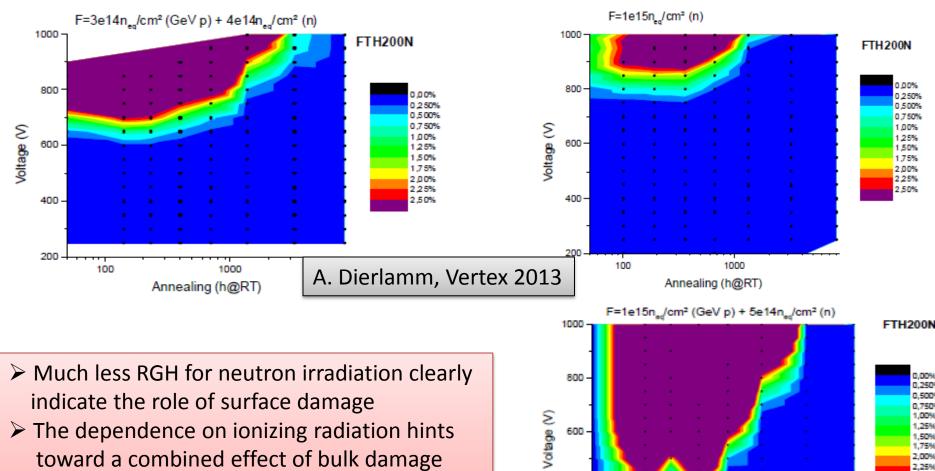
10e14n_{ed}/cm² neutrons

15e14n ... / cm² mixed

Annealing (h@RT)

1000

2,50%



400

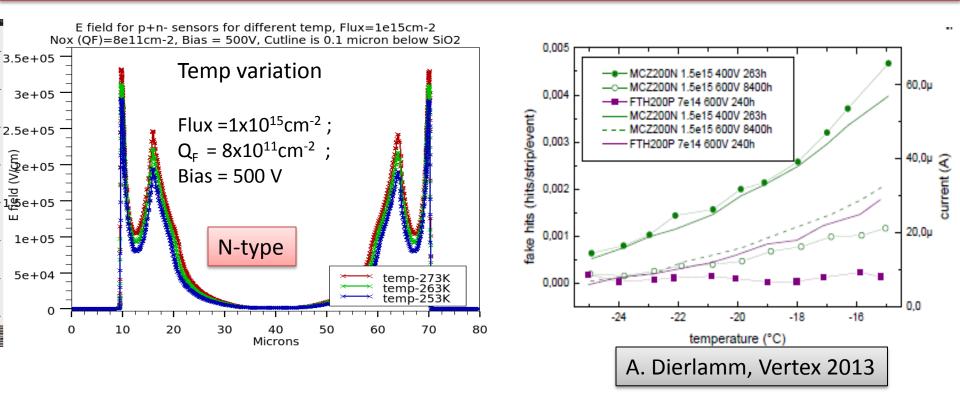
200

100

and surface damage

The Q_F effect simulation were carried out before these measurements

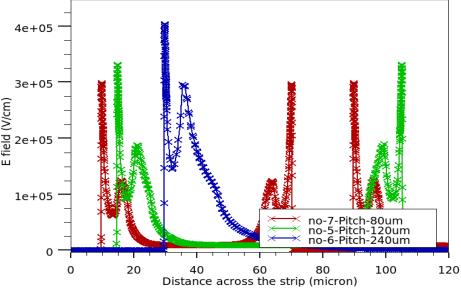
E field for p-in-n sensor : Effect of temp. variation



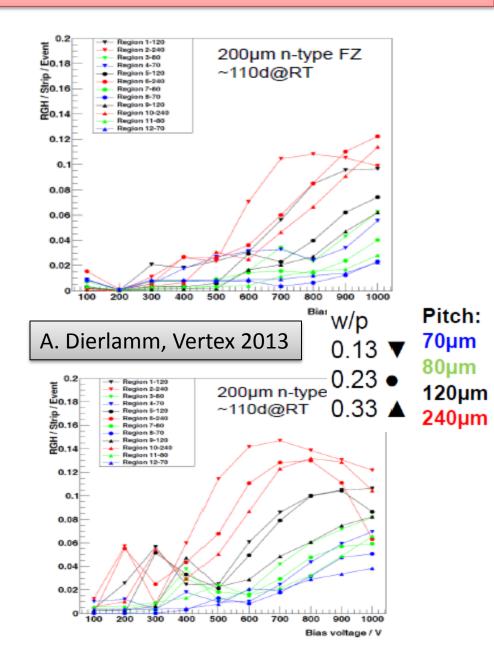
Simulations shows small increase of Maximum Electric field with increase in temperature
 Measured RGH rate also increases with increase in temperature.

Effect of strip pitch variation on E field

E Field 0.1micron below SiO2/Si interface for p+n- sensors at 253K Fluence = 5e14cm-2, Oxide charge density = 8e11cm-2, Bias = 800V



- Simulated maximum E field near p+ curvature, just below SiO2/Si interface increases with increase in strip pitch
- \succ RGH also follow the similar trend.
- \blacktriangleright Maximum RGH are for 240µm strip pitch.



Summary/future outlooks

➢ No significant difference in C_{int} values for p-type and n-type sensors

Similarly, good R_{int} can be expected for p-type sensors after irradiation, even for moderate/low p-stop doping density.

➢Critical electric field study

▶ P-type (n-in-p) sensors intrinsically better (compare to n-type) after irradiation

- lower electric fields at the strips side

(However high electric field appear on p-stop implant for high p-stop doping dose after irradiation – Avoid high p-stop doing)

► Non Gaussian noise problem

Very high E field may be cause of non-Gaussian noise events in irradiated sensors

▶p+n- sensors are more prone to micro-discharge problem

Simulations and measurements produce similar trends

Edge TCT (Kramberger, Marcos) and TCT results will be used to further tune the bulk damage models

Study to decrease the no. of traps in bulk damage model is going on

Thanks for your attention!

17 institutes currently involved in CMS-HPK Phase-II

tracker upgrade campaign



Device Simulation Group - Aims:

- Provide input to the CMS sensor designs
- Points under investigation:
 - -- Device design simulate capacitances, verify isolation techniques
- Charge collection and read-out, research optimal layout
- ✤ Radiation damage modeling of sensors → derive a trap model
- Comparison of simulation tools

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